

Title (en)
MICROSCOPE COMPRISING SCANNING OPTICAL SYSTEM

Title (de)
MIKROSKOP MIT OPTISCHEM ABTASTSYSTEM

Title (fr)
MICROSCOPE COMPRENANT SYSTÈME OPTIQUE DE BALAYAGE

Publication
EP 3098642 A1 20161130 (EN)

Application
EP 16170121 A 20160518

Priority
JP 2015110115 A 20150529

Abstract (en)
For achieving an expanded observation range without sacrificing resolution, a scanning optical system (1) according to the present invention includes a scanner (11) that deflects laser light from a light source while changing a deflection angle of the laser light; a polarization beam splitter (15) that is capable of splitting-off the laser light from an optical path of the laser light deflected by the scanner (11); a polarization beam splitter (19) that is disposed between the light source and the scanner (11) and that causes the laser light split-off by the polarization beam splitter (15) to travel toward the scanner (11); and a first relay optical system (17) that has 1x relay magnifying power and that is disposed between the polarization beam splitter (15) and the polarization beam splitter (19). The first relay optical system (17) relays the laser light split-off by the polarization beam splitter (15) so as to cause the laser light to be incident again on the scanner (11) at the same position as an incident position of the laser light from the light source via the polarization beam splitter (19).

IPC 8 full level
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Citation (applicant)
JP 2010085826 A 20100415 - OLYMPUS CORP

Citation (search report)
• [A] US 2013301096 A1 20131114 - TAKAHASHI SHINTARO [JP]
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CN110546548A; CN114930224A; US11237402B2; US11698538B2; WO2021076292A1

Designated contracting state (EPC)
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DOCDB simple family (application)
EP 16170121 A 20160518; JP 2015110115 A 20150529; US 201615155965 A 20160516